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IN THE CLAIMS:

Claim 1. (Currently Amended) A bottom-gate thin-film transistor comprising:

a gate electrode, a gate insulating film, an active layer, and a protective insulating film deposited in that order on a substrate; and

various a plurality of layers formed over said protective film with at least one electrode extending therethrough that is operatively and electrically connected to one of said active layer, an LDD region or and a source-drain region;

wherein[[,]] the protective insulating film has a thickness of 100 nm or less, and the protective Insulating film is formed on any one of the active layer, [[an]] LDD region, and [[a]] source-drain region, and

wherein there is no etched mask structure within the thin film transistor structure.

Claim 2. (Original) A bottom-gate thin-film transistor according to Claim 1, wherein the active layer comprises a polysilicon film.

Claim 3. (Original) A bottom-gate thin-film transistor according to either Claim 1 or 2, wherein the protective insulating film has a thickness of 5 to 50 nm.

Claims 4-9. (Canceled)

Claim 10. (Withdrawn)

Claim 11. (Canceled)

Claim 12. (Withdrawn)

Claim 13. (Canceled)

